

| Sheet 1 of 1 | | | | | | | | INFORMATION DISCLOSURE STATEMENT | | | | | | | |
|---|----|--|------|---------------------------------------|-------|----------|-------------|----------------------------------|-------------------------------|--|--|--|--|--|--|
| FORM PTO/SB/08 A&B (modified) | | | | ATTY DOCKET NO. 2003_1187A | | | | SERIAL NO. 10644,738 | | | | | | | |
| U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE | | | | APPLICANT Tsuyoshi NAKAMURA et al. | | | | | | | | | | | |
| LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary) | | | | FILING DATE August 21, 2003 | | | | GROUP 1795 | | | | | | | |
| Date Submitted to PTO: March 22, 2011 | | | | | | | | | | | | | | | |
| U.S. PATENT DOCUMENTS | | | | | | | | | | | | | | | |
| *EXAMINER INITIAL | | DOCUMENT NUMBER | DATE | NAME | | | CLASS | SUBCLASS | FILING DATE IF APPROPRIATE | | | | | | |
| | | AA | | | | | | | | | | | | | |
| | | AB | | | | | | | | | | | | | |
| | | AC | | | | | | | | | | | | | |
| | | AD | | | | | | | | | | | | | |
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| | | AI | | | | | | | | | | | | | |
| FOREIGN PATENT DOCUMENTS | | | | | | | | | | | | | | | |
| | | DOCUMENT NUMBER | DATE | COUNTRY | CLASS | SUBCLASS | TRANSLATION | | | | | | | | |
| | | | | | | | YES | NO | | | | | | | |
| | | BA | | | | | | | | | | | | | |
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| | | BC | | | | | | | | | | | | | |
| | | BD | | | | | | | | | | | | | |
| | | BE | | | | | | | | | | | | | |
| OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.) | | | | | | | | | | | | | | | |
| | CA | T. Kijima et al., "Low Temperature Deposition of Bi ₄ Ti ₃ O ₁₂ Thin Films by MOCVD", Functional Devices Lab. Sharp Corp., with "Concise Explanation of the Relevance with Respect to Extended Abstracts (The 42nd Spring Meeting, 1995); The Japan Society of Applied Physics and Related Societies", 29p-D-2. | | | | | | | | | | | | | |
| | CB | H. Watanabe et al., "Development of Y1 Materials (Bi Layer Structured Ferroelectrics) Thin-Film Capacitors (II)", Olympus Optical Co., Ltd. *Symetrix Co., with "Concise Explanation of the Relevance with Respect to Extended Abstracts (The 55th Autumn Meeting, 1994); The Japan Society of Applied Physics", 20p-M-19. | | | | | | | | | | | | | |
| | CC | Jun-Sung Chun et al., "Toward 0.1µm Contact Hole Process by Using Water Soluble Organic Over-Coating Material (WASOOM); Resist Flow Technique (III); Study on WASOOM, Top Flare and Etch Characterization", Advances in Resist Technology and Processing XVIII, Proceedings of SPIE, Vol. 4345 (2001), pages 647-654. | | | | | | | | | | | | | |
| | CD | S. Satoh et al., "Electrical Properties of Bi ₄ Ti ₃ O ₁₂ Thin Films by MOCVD", Functional Devices Lab. Sharp Corp., with "Concise Explanation of the Relevance with Respect to Extended Abstracts (The 42nd Spring Meeting, 1995); The Japan Society of Applied Physics and Related Societies", 29p-D-3. | | | | | | | | | | | | | |
| EXAMINER /Christopher Young/ (04/25/2011) | | | | DATE CONSIDERED 04/25/2011 | | | | | | | | | | | |

ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /CY/

*Examiner: initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.